## IN THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

## 1-18. (Canceled)

- 19. (New) A scrub cleaning device comprising:
- a pair of scrubbers for rotating around a central shaft and conveying a substrate with the substrate rotatably held;
  - a substrate inlet section for introducing the substrate between the pair of scrubbers;
- a first cleaning station for temporarily stopping the substrate being conveyed by the pair of scrubbers to the rotation of the pair of scrubbers and rotating the substrate at the stop position with a rotation axis of the substrate fixed, to perform a scrub cleaning of the substrate; and
- a second cleaning station for generating a speed difference on the substrate being conveyed by the pair of scrubbers to the rotation of the pair of scrubbers and rotating the substrate while conveying the substrate with the rotation axis of the substrate not fixed, to perform a subsidiary scrub cleaning of the substrate.
  - 20. (New) A scrub cleaning device comprising:
- a pair of scrubbers for rotating around a central shaft and conveying a substrate with the substrate rotatably held;
  - a substrate inlet section for introducing the substrate between the pair of scrubbers;

a stopper mechanism for abutting the substrate being conveyed by the pair of scrubbers to temporarily stop the substrate to the rotation of the pair of scrubbers; and

a guide member for abutting the substrate being conveyed by the pair of scrubbers to guide the conveyance of the substrate, the guide member being disposed along the conveyance direction of the substrate,

wherein a scrub cleaning of the substrate is performed by rotating the substrate at the stop position with a rotation axis of the substrate fixed, by the stopper mechanism, and a subsidiary scrub cleaning is performed by rotating the substrate while conveying the substrate with the rotation axis of the substrate not fixed, by the guide member.

- 21. (New) The scrub cleaning device according to Claim 19 or 20, comprising cleaning liquid supply means for supplying a cleaning liquid to at least one of the pair of scrubbers and the substrate held between the pair of scrubbers.
- 22. (New) The scrub cleaning device according to Claim 19 or 20, comprising a substrate outlet section for discharging the substrate being conveyed by the pair of scrubbers from between the pair of scrubbers.
- 23. (New) The scrub cleaning device according to Claim 20, comprising a sensor for confirming the presence/absence of the substrate in the stopper mechanism, wherein the substrate inlet section introduces the substrate between the pair of scrubbers when absence of the substrate is confirmed by the sensor.

- 24. (New) A scrub cleaning device comprising:
- a plurality of cleaning stations comprising constitutions according to Claim 19 or 20; and a conveyance mechanism for conveying a substrate cleaned in the cleaning station to the next cleaning station in said plurality of cleaning stations.
- 25. (New) The scrub cleaning device according to Claim 24, wherein said conveyance mechanism comprises a guide member for connecting the scrubbers of said plurality of cleaning stations to one another.
- 26. (New) The scrub cleaning device according to Claim 24, wherein said conveyance mechanism comprises a guide member for connecting the scrubbers of said plurality of cleaning stations to one another, and a scrub roller for holding the substrate along the guide member from opposite sides and conveying the substrate.
- 27. (New) The scrub cleaning device according to Claim 19 or 20, wherein the pair of scrubbers is disposed vertically.
- 28. (New) The scrub cleaning device according to Claim 19 or 20, wherein the substrate is a glass substrate for an information recording medium.